

ABSTRACT

1 A semiconductor workpiece processing system comprising at
2 least one processing tool, a container, a first transport
3 section, and a second transport section. The processing
4 tool is used for processing semiconductor workpieces.
5 The container is used for holding at least one
6 semiconductor workpiece therein for transporting two and
7 from the processing tool. The first transport section is
8 connected to the processing tool for transporting the
9 container to and from the processing tool. The second
10 transport section is connected to the first transport
11 section for transporting the container to and from the
12 processing tool. The first transport section is vehicle
13 based having a transport vehicle capable of holding the
14 container and moving along a first track of the first
15 transport section. The second transport section is not
16 vehicle based and has a second track with at least one
17 support element thereon adapted to interface with the
18 container for movably supporting the container from the
19 second track and allowing the container to move relative
20 to the first track. The first track and second track are
21 disposed proximate to each other to allow the container
22 to moved therebetween in one move.